



IRW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Noriyoshi SATO et al.

Group Art Unit: 2891

Application No.: 10/539,569

Examiner: C. EVERHART

Filed: August 18, 2005

Docket No.: 124305

For: PLASMA GENERATOR, OZONE GENERATOR, SUBSTRATE PROCESSING  
APPARATUS AND METHOD OF MANUFACTURING SEMICONDUCTOR  
DEVICE

**STATEMENT OF SUBSTANCE OF THE INTERVIEW**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

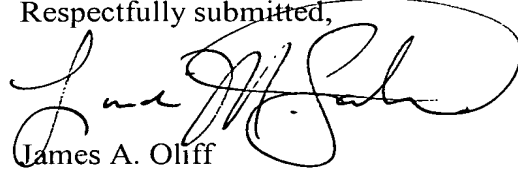
Sir:

Applicants appreciate the courtesies shown to Applicants' representatives by Examiner Everhart in the September 5 personal interview. Applicants' separate record of the substance of the interview is incorporated into the following remarks.

During the interview, Applicants' representatives presented arguments corresponding to Applicants' Request for Reconsideration filed on August 29, 2008. Applicants' representatives ensured that the Examiner understood the presently claimed subject matter and explained to the Examiner the deficiencies in the applied references.

Should any questions arise regarding this submission, all inquiries may be directed to Applicant's undersigned representatives at the telephone number set forth below.

Respectfully submitted,



James A. Oliff

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JAO:LMS/dqs

Date: September 9, 2008

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